



EV077335270

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/388,826
Filing Date September 1, 1999
Inventor Weimin Li et al.
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner E.J. Kielin
Attorney's Docket No. MI22-1208
Title: Low k Interlevel Dielectric Layer Fabrication Methods

RESPONSE TO JUNE 4, 2002 OFFICE ACTION

#28/F
9/12/02
Jumo

To: Box Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

From: Frederick M. Fliegel, Ph.D.
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601 W. First Avenue, Suite 1300
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Sir:

Responsive to the Office Action dated June 4, 2002, Applicant amends
and remarks as follows: